

Notice of References Cited	Application/Control No. 10/728,172		Applicant(s)/Patent Under Reexamination GATTIKER ET AL.	
	Examiner Leigh Marie Garbowski		Art Unit 2825	Page 1 of 1

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*	C	US-6,574,760	06-2003	Mydill, Marc	714/724
*	D	US-6,184,048	02-2001	Ramon, Joseph	438/14
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NON-PATENT DOCUMENTS

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*	U	GATTIKER et al., "Current Signatures," 14th VLSI Test Symposium, IEEE 1996, pages 112-117.			
*	V	MAXWELL et al., "Current Ratios: A Self-Scaling Technique for Production IDDQ Testing," ITC Int'l Test Conference, IEEE 1999, pages 738-746.			
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	X	SODEN et al., "IDDQ Testing and Defect Classes - A Tutorial," IEEE 1995 Custom ICs Conference, pages 633-642.			

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.